

DOCKET NO: 267154US26PCT

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :
HONGYU YUE, ET AL. : EXAMINER: GOUDREAU, G. A.
SERIAL NO: 10/531,469 :
FILED: APRIL 15, 2005 : GROUP ART UNIT: 1792
FOR: METHOD AND APPARATUS FOR :
DETERMINING AN ETCH PROPERTY
USING AN ENDPOINT SIGNAL

ELECTION

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

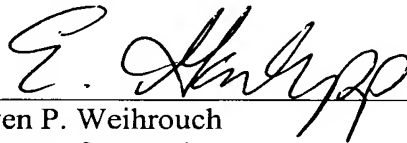
SIR:

In response to the Election Requirement dated February 4, 2009, Applicant(s) elect Group I, identified in the outstanding Office Action as corresponding to Claims 20-41, drawn to a method for plasma etching a substrate. Applicant(s) reserve the right to file one or more divisional applications directed to the non-elected invention.

Accordingly, examination on the merits of Claims 20-41 is believed to be in order and an early and favorable action is respectfully requested.

Respectfully submitted,

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